

1765
PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Continuation-in-part application of: ZHU et al.

Attorney Docket No.: LAM1P147/P0675

Application No.: 09/782,185

Examiner: CHEN, Kin-Chan

Filed: February 12, 2001

Group: 1765

Title: UNIQUE PROCESS CHEMISTRY FOR
ETCHING ORGANIC LOW-K MATERIALS

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail to: Box Non-Fee Amendment, Commissioner for Patents, Washington, D.C. 20231 on March 25, 2003.

Signed: Sue Funchess

Sue Funchess

AMENDMENT C TRANSMITTAL

Box Non-Fee Amendment
Commissioner for Patents
Washington, D.C. 20231

RECEIVED
APR 04 2003
GROUP 1700

Sir:

Transmitted herewith is an Amendment in the above-identified application.

The fee has been calculated as shown below.

	Claims After Amendment		Highest Previously Paid For	Present Extra	Small Entity Rate Fee	Large Entity Rate Fee
Total Claims	19	MINUS	20	0	x 9 =	x 18 = \$-0-
Independent Claims	1	MINUS	3	0	x 42 =	x 84 = \$-0-
Multiple Dependent Claim Present and Fee Not Previously Paid					\$140.00	\$280.00
Total					\$	\$-0-

- ☐ Applicant(s) hereby petition for a _____ month extension(s) of time to respond to the aforementioned Office Action.
- ☒ Applicant(s) believe that no (additional) Extension of Time is required; however, if it is determined that such an extension is required, Applicant(s) hereby petition that such an extension be granted and authorize the Commissioner to charge the required fees for an Extension of Time under 37 CFR 1.136 to Deposit Account No. 50-0388 (Order No. LAM1P147).
- ☐ Enclosed is our Check No. _____ in the amount of \$_____ to cover the additional claim fee and/or extension of time fees.
- ☒ Please charge the required fees, or any additional fees required to facilitate filing the enclosed response, to Deposit Account No. 50-0388 (Order No. LAM1P147).

Respectfully submitted,
BEYER WEAVER & THOMAS, LLP

Michael Lee
Michael Lee
Reg. No. 31,846

P.O. Box 778
Berkeley, CA 94704-0778



PATENT

#13
4/2/03

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: ZHU et al.

Attorney Docket No.: LAM1P147/P0675

Application No.: 09/782,185

Examiner: CHEN, Kin-Chan

Filed: February 12, 2001

Group: 1765

Title: UNIQUE PROCESS CHEMISTRY FOR
ETCHING ORGANIC LOW-K MATERIALSCERTIFICATE OF MAILING

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Signed: _____

Sue Funchess

AMENDMENT C

Box Non-Fee Amendment
Commissioner for Patents
Washington, D.C. 20231

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Dear Sir:

In response to the Office Action dated December 30, 2002, please consider the following:

REMARKS

Claims 19-37 are pending.

The Examiner rejected claims 19-37 under 35 U.S.C. § 103, as being unpatentable over Tao et al. (US 6,194,128B1) in view of Ye et al. (US 6,080,529).

Regarding claim 19, Ye does not teach that the oxygen/nitrogen base plasma of col. 12, lines 28-30 of Ye may be replaced with a hydrogen/nitrogen based plasma that is especially useful for etching organic low-k dielectric in a multiple layer substrate, as argued by the Examiner. Col. 12, lines 25-31, of Ye teaches a chemistry of oxygen and nitrogen to etch an α -